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I, ***Dr. Graham Fisher, Director of Intellectual Property*** of ***MEMC Electronic Materials, Inc.***, the Assignee of the entire right, title, and interest in the ***U.S. Patent Application(s) and/or Patent(s) identified on the attached Schedule A***, hereby revoke all previous powers of attorney or authorizations of agent given and do hereby appoint the attorneys or agents associated with the following Customer Number, with full power of substitution and revocation, to prosecute and transact all business in the Patent and Trademark Office connected therewith for the ***U.S. Patent Application(s) and/or Patent(s) listed in the attached Schedule A:***

Customer Number: 76681

Please direct all correspondence in connection with said ***U.S. Patent Application(s) and/or Patent(s)*** to:

Customer Number: 76681

Respectfully submitted,

Date: 5/13/2008

Dr. Graham Fisher
Director of Intellectual Property
MEMC Electronic Materials, Inc.

PATENT

THE UNITED STATES PATENT AND TRADEMARK OFFICE

STATEMENT UNDER 37 CFR 3.73(b)

MEMC Electronic Materials, Inc., a Delaware Corporation, pursuant to 37 CFR 3.73(b), hereby states that it is the Assignee of the entire right, title, and interest in ***U.S. Patent Application(s) and/or Patent(s) on the attached Schedule A.***

The entire rights, title, and interest in the aforementioned Patent Application(s) and/or Patent(s) were conveyed to ***MEMC Electronic Materials, Inc.*** via Assignment(s) recorded with the United States Patent and Trademark Office at the ***Reel/Frame Numbers on the attached Schedule A.***

The undersigned, ***Dr. Graham Fisher, Director of Intellectual Property,*** has full authorization to act on behalf of Assignee ***MEMC Electronic Materials, Inc.***

Respectfully submitted,

Date: 5/13/2008

Dr. Graham Fisher
Director of Intellectual Property
MEMC Electronic Materials, Inc.

APPENDIX A
Owned by MEMC Electronic Materials, Inc.

ATTORNEY REFERENCE	CONF. NO	PUBLICATION NO. & DATE	SERIAL NO. FILING DATE	PATENT NO. ISSUE DATE	CURRENT OWNER/ ASSIGNEE	REEL AND FRAME NO.	TITLE
MEMC3043.1	3075		08/820,593 3/19/1997	5,834,812 11/10/1998	MEMC Electronic Materials, Inc.	Division of 08/346,695 recorded at 007321/0390	EDGE STRIPPED BESOI WAFER
MEMC3053	5338	US2005-0016443 A1 1/27/2005	10/623,967 7/21/2003	6,960,254 11/1/2005	MEMC Electronic Materials, Inc.	014312/0399	METHOD TO MONITOR AND CONTROL THE CRYSTAL COOLING OR QUENCHING RATE BY MEASURING CRYSTAL SURFACE TEMPERATURE
28744-153 (MEMC3054)	5584	US2007-0074653-A1 4/5/2007	11/241,413 9/30/2005		MEMC Electronic Materials, Inc.	016876/0126	APPARATUS FOR PREPARATION OF SILICON CRYSTALS WITH REDUCED METAL CONTENT
MEMC3057	3609	US2004-0235402A1 11/25/2004	10/442,900 5/20/2003	7,008,308 3/7/2006	MEMC Electronic Materials, Inc.	013778/0718	WAFER CARRIER
MEMC3067.1	6672	US-2006-0011588-A1 1/19/2006	11/152,362 6/14/2005	7,323,421 1/29/2008	MEMC Electronic Materials, Inc.	016596/0425	SILICON WAFER ETCHING PROCESS AND COMPOSITION
28744-217 (MEMC3070.1)	9113	US-2006-0138601-A1 6/29/2006	11/104,544 4/13/2005		MEMC Electronic Materials, Inc.	016200/0855	INTERNALLY GETTERED HETEROEPITAXIAL SEMICONDUCTOR WAFERS AND METHODS OF MANUFACTURING SUCH WAFERS
MEMC3073	8463	US2005-0250297 A1 11/10/2005	10/840,854 5/7/2004	7,084,048 8/1/2006	MEMC Electronic Materials, Inc.	014971/0329	PROCESS FOR METALLIC CONTAMINATION REDUCTION IN SILICON WAFERS
28744-108 (MEMC3077.1)	1776	US2006-0016389 A1 1/26/2006	10/898,148 7/23/2004		MEMC Electronic Materials, Inc.	015337/0767	PARTIALLY DEVITRIFIED CRUCIBLE
MEMC3077.1	7816	US-2005-0279277-A1 12/22/2005	10/930,654 8/31/2004	7,291,222 11/6/2007	MEMC Electronic Materials, Inc.	015390/0001	SYSTEMS AND METHODS FOR MEASURING AND REDUCING DUST IN GRANULAR MATERIAL
28744-157 (MEMC3084.1)	4539	US-2005-0279278-A1 12/22/2005	11/155,385 6/17/2005		MEMC Electronic Materials, Inc.	016706/0613	MELTER ASSEMBLY AND METHOD FOR CHARGING A CRYSTAL FORMING APPARATUS WITH MOLTEN SOURCE MATERIAL
MEMC3084.4	3753	US-2005-0279276-A1 12/22/2005	11/155,105 6/17/2005	7,344,594 3/18/2008	MEMC Electronic Materials, Inc.	016864/0061	MELTER ASSEMBLY AND METHOD FOR CHARGING A CRYSTAL FORMING APPARATUS WITH MOLTEN SOURCE MATERIAL
28744-158 (MEMC3084.5)	3746	US-2005-0279275-A1 12/22/2005	11/155,104 6/17/2005		MEMC Electronic Materials, Inc.	016833/0100	MELTER ASSEMBLY AND METHOD FOR CHARGING A CRYSTAL FORMING APPARATUS WITH MOLTEN SOURCE MATERIAL
MEMC3087	6527	US-2006-0144320-A1 7/6/2006	11/027,360 12/30/2004	7,291,221 11/6/2007	MEMC Electronic Materials, Inc.	016141/0710	ELECTROMAGNETIC PUMPING OF LIQUID SILICON IN A CRYSTAL GROWING PROCESS
28744-104 (MEMC3091)	8236	US-2007-0105279-A1 5/10/2007	11/270,790 11/9/2005		MEMC Electronic Materials, Inc.	017763/0557	ARSENIC AND PHOSPHORUS DOPED SILICON WAFER SUBSTRATES HAVING INTRINSIC GETTERING
28744-110 (MEMC3092.1)	8370	US-2006-0263967-A1 11/23/2006	11/436,688 5/18/2006		MEMC Electronic Materials, Inc.	017945/0383	HIGH RESISTIVITY SILICON STRUCTURE AND A PROCESS FOR THE PREPARATION THEREOF
28744-105 (MEMC3098)	8334	US2006-0024969 A1 2/2/2006	10/900,938 7/27/2004		MEMC Electronic Materials, Inc.	015284/0081	METHOD FOR PURIFYING SILICON CARBIDE COATED STRUCTURES
MEMC3101	1084	US-2006-0144321-A1 7/6/2006	11/026,780 12/30/2004	7,223,304 5/29/2007	MEMC Electronic Materials, Inc.	016157/0533	CONTROLLING MELT-SOLID INTERFACE SHAPE OF A GROWING SILICON CRYSTAL USING A VARIABLE MAGNETIC FIELD
MEMC3104	4334		11/041,593 1/24/2005	7,033,168 4/25/2006	MEMC Electronic Materials, Inc.	015891/0655	SEMICONDUCTOR WAFER BOAT FOR A VERTICAL FURNACE